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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/695,727	10/28/2003	Craig M. Carpenter	MI22-2433	5546
21567	7590	05/03/2006	EXAMINER	
WELLS ST. JOHN P.S. 601 W. FIRST AVENUE, SUITE 1300 SPOKANE, WA 99201			MOORE, KARLA A	
			ART UNIT	PAPER NUMBER

1763

DATE MAILED: 05/03/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary

Application No.

10/695,727

Applicant(s)

CARPENTER ET AL.

Examiner

Karla Moore

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --
Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 10 February 2006.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 77-88,95-103,108-122,125 and 126 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☒ Claim(s) 77-88,95-103 and 108-120 is/are allowed.
- 6) ☒ Claim(s) 121,122,125 and 126 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 28 October 2003 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
- ☐ Certified copies of the priority documents have been received.
 - ☐ Certified copies of the priority documents have been received in Application No. _____.
 - ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|------------------------------------------------------------------------------------------------------------------------|-----------------------------------------------------------------------------------------|
| 1) <input type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Claim Rejections - 35 USC § 103

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

2. Claims **121-122** are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent No. 6,089,543 to Freerks in view of U.S. Patent No. 5,223,113 to Kaneko et al., U.S. Patent No. 5,484,483 to Kyogoku, U.S. Patent No. 6,045,620 to Tepman et al. and U.S. Patent No. 4,289,061 to Emmett.

3. Freerks discloses a semiconductor substrate processing chamber and accessory attachment interfacial structure substantially as claimed and comprising: a body (Figures 3 and 6, 28, 30, 32, 34) sized and shaped to engage between a semiconductor substrate processing chamber (Figure 1, 14) and an accessory attachment (Figure 1, 12) which is exposed to the processing chamber, the body having first and second faces; the body comprising an external perimeter extending between the first and second faces; and the body comprising a volume in at least one cross section region which extends to diametrically opposing portions of the perimeter.

4. However, Freerks et al. fail to teach the body comprising a volume in at least one cross section region, at least a majority of said cross sectional region constituting a mass of substantially non-metallic and thermally insulative material, the mass being sufficient to effectively reduce heat transfer between the semiconductor processing chamber and the accessory attachment when so engaged than would otherwise occur in the absence of said mass of material when so engaged.

5. Kaneko et al. teach the use of ceramic material at a peripheral portion of a contacting interface between two chambers for purpose of providing excellent heat insulation, which enables power consumption of the heater (in a processing chamber) to be made smaller and the temperature control of the process chamber to be made easier (column 2, rows 45-48; column 5, rows 44-46; column 7, rows

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38-44; and column 8, rows 6-14). Kaneko teaches the use of a clearance (Figure 5, C1) the ceramic, insulating material for the purpose of preventing contact between two metallic surfaces, thus allowing heat to be transferred only through convection (column 7, rows 45-54). The mass of material of Kaneko et al. comprises openings extending through the mass of material for fixedly attaching the mass of material (column 5, rows 44-51).

6. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided non-metallic, thermally insulating material peripheral to a metallic passageway in Freerks in order to provide excellent heat insulation, enabling power consumption of the heater (in a processing chamber) to be made smaller and the temperature control of the process chamber to be made easier as taught by Kaneko et al. It would have been further obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a clearance created by ceramic, insulating material in Freerks in order to prevent any heat transfer other than by convection as taught by Kaneko et al.

7. Freerks and Kaneko et al. disclose the invention substantially as claimed and as described above.

8. However, Freerks and Kaneko et al. fail to teach the accessory attachment as something other than a transfer chamber that attaches with a housing of a processing chamber and communicates with the chamber.

9. Kyogoku teach the use of an accessory attachment interfacial structure (Figure 3, 8; column 3, row 55 through column 4, row 3) between a processing chamber and a vent line for the purpose of insulating before and after the vent for the purposes of preventing heat from escaping and improving the average thermal characteristic of a heating unit.

10. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided an accessory interfacial structure in an apparatus such as the one described in Freerks and Kaneko et al. for insulating between a processing chamber and a vent in order to prevent heat from escaping and to improve the average thermal characteristic of a heating unit as taught by Kyogoku.

11. Freerks, Kaneko et al. and Kyogoku disclose the invention substantially as claimed and as described above.

12. However, Freerks, Kaneko et al. and Kyogoku fail to teach the interfacial structure comprising a plurality of openings for receiving load bearing plugs.

13. Tepman et al. teach the use of a plurality of openings and supplying a plurality of screws (or other appropriate means) to those openings in order to attach the interfacial structure to a transfer chamber (column 4, row 65 through column 5, row 1 and column 5, rows 35-36).

14. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a plurality of openings and to have supplied a plurality of screws to those openings in Freerks, Kaneko et al. and Kyogoku in order to attach an interfacial structure to a transfer chamber as taught by Tepman et al.

15. Freerks, Kaneko et al., Kyogoku and Tepman disclose the invention substantially as claimed and as described above.

16. However, Freerks, Kaneko et al., Kyogoku and Tepman fail to teach the body comprising load bearing plugs within at least some of the openings in the thermally insulative material, the load bearing plugs having greater compression strength than the thermally insulative material and at least some of the load bearing plugs comprising holes extending therethrough which are sized to received mounting bolts.

17. Emmett teaches the use load bearing plugs (Figure 1, 2) including a hollow portion sized to receive mounting bolts (20) where the purpose of the hollow portion is to absorb a substantial amount of the total load applied by the plug (column 2, rows 41-49). The load bearing plugs have outer longitudinal surfaces which are not threaded (column 1, rows 53-64).

18. It would have been obvious to one of ordinary skill in art at the time the Applicant's invention was made to have provided at least some of load bearing plugs with a hollow portion in Freerks, Kaneko et al. and Tepman in order to absorb a substantial amount of the total load applied by the plug as taught by Emmett.

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19. With respect to claims 122 and 124, as noted above, Emmett teaches the use of load bearing plugs including a hollow portion.

20. Claims **125 and 126** are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent No. 6,089,543 to Freerks in view of U.S. Patent No. 5,223,113 to Kaneko et al., U.S. Patent No. 5,484,483 to Kyogoku, U.S. Patent No. 6,045,620 to Tepman et al., U.S. Patent No. 4,289,061 to Emmett and U.S. Patent No. 1,686,468 to Rosenberg.

21. Freerks discloses a semiconductor substrate processing chamber and accessory attachment interfacial structure substantially as claimed and comprising: a body (Figures 3 and 6, 28, 30, 32, 34) sized and shaped to engage between a semiconductor substrate processing chamber (Figure 1, 14) and an accessory attachment (Figure 1, 12) which is exposed to the processing chamber, the body having first and second faces; the body comprising an external perimeter extending between the first and second faces; and the body comprising a volume in at least one cross section region which extends to diametrically opposing portions of the perimeter.

22. However, Freerks et al. fail to teach the body comprising a volume in at least one cross section region, at least a majority of said cross sectional region constituting a mass of substantially non-metallic and thermally insulative material, the mass being sufficient to effectively reduce heat transfer between the semiconductor processing chamber and the accessory attachment when so engaged than would otherwise occur in the absence of said mass of material when so engaged.

23. Kaneko et al. teach the use of ceramic material at a peripheral portion of a contacting interface between two chambers for purpose of providing excellent heat insulation, which enables power consumption of the heater (in a processing chamber) to be made smaller and the temperature control of the process chamber to be made easier (column 2, rows 45-48; column 5, rows 44-46; column 7, rows 38-44; and column 8, rows 6-14). Kaneko teaches the use of a clearance (Figure 5, C1) the ceramic, insulating material for the purpose of preventing contact between two metallic surfaces, thus allowing heat to be transferred only through convection (column 7, rows 45-54). The mass of material of Kaneko

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et al. comprises openings extending through the mass of material for fixedly attaching the mass of material (column 5, rows 44-51).

24. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided non-metallic, thermally insulating material peripheral to a metallic passageway in Freerks in order to provide excellent heat insulation, enabling power consumption of the heater (in a processing chamber) to be made smaller and the temperature control of the process chamber to be made easier as taught by Kaneko et al. It would have been further obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a clearance created by ceramic, insulating material in Freerks in order to prevent any heat transfer other than by convection as taught by Kaneko et al.

25. Freerks and Kaneko et al. disclose the invention substantially as claimed and as described above.

26. However, Freerks and Kaneko et al. fail to teach the accessory attachment as something other than a transfer chamber that attaches with a housing of a processing chamber and communicates with the chamber.

27. Kyogoku teach the use of an accessory attachment interfacial structure (Figure 3, 8; column 3, row 55 through column 4, row 3) between a processing chamber and a vent line for the purpose of insulating before and after the vent for the purposes of preventing heat from escaping and improving the average thermal characteristic of a heating unit.

28. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided an accessory interfacial structure in an apparatus such as the one described in Freerks and Kaneko et al. for insulating between a processing chamber and a vent in order to prevent heat from escaping and to improve the average thermal characteristic of a heating unit as taught by Kyogoku.

29. Freerks, Kaneko et al. and Kyogoku disclose the invention substantially as claimed and as described above.

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30. However, Freerks, Kaneko et al. and Kyogoku fail to teach the interfacial structure comprising a plurality of openings for receiving load bearing plugs.

31. Tepman et al. teach the use of a plurality of openings and supplying a plurality of screws (or other appropriate means) to those openings in order to attach the interfacial structure to a transfer chamber (column 4, row 65 through column 5, row 1 and column 5, rows 35-36).

32. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a plurality of openings and to have supplied a plurality of screws to those openings in Freerks, Kaneko et al. and Kyogoku in order to attach an interfacial structure to a transfer chamber as taught by Tepman et al.

33. Freerks, Kaneko et al., Kyogoku and Tepman disclose the invention substantially as claimed and as described above.

34. However, Freerks, Kaneko et al., Kyogoku and Tepman fail to teach the body comprising load bearing plugs within at least some of the openings in the thermally insulative material, the load bearing plugs having greater compression strength than the thermally insulative material and at least some of the load bearing plugs comprising holes extending therethrough which are sized to received mounting bolts.

35. Emmett teaches the use load bearing plugs (Figure 1, 2) including a hollow portion sized to receive mounting bolts (20) where the purpose of the hollow portion is to absorb a substantial amount of the total load applied by the plug (column 2, rows 41-49). The load bearing plugs have outer longitudinal surfaces which are not threaded (column 1, rows 53-64).

36. It would have been obvious to one of ordinary skill in art at the time the Applicant's invention was made to have provided at least some of load bearing plugs with a hollow portion in Freerks, Kaneko et al. and Tepman in order to absorb a substantial amount of the total load applied by the plug as taught by Emmett.

37. Freerks, Kaneko et al., Kyogoku, Tepman and Emmett disclose the invention substantially as claimed and as described above.

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38. However, Freerks, Kaneko et al., Kyogoku, Tepman and Emmett fail to teach at least some of the load bearing plugs having at least one radial projection, the body comprising interlocking openings sized to receive said radial projections effective to preclude rotation of said load bearing plugs having the radial projection.

39. Rosenberg teaches the use of load bearing plugs comprising radial projections interlocking with openings sized to receive said radial projections in a device for fastening two parts together for the purpose of providing a fastener capable of affording a great amount of frictional resistance to any stress tending to withdraw the fastener (page 1, column 2, rows 73-99). The interlocking openings are created upon insertion of the load bearing plug.

40. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a fastener with radial projections and corresponding interlocking openings in Freerks, Kaneko et al., Kyogoku, Tepman and Emmett in order to provide a fastener capable of affording a great amount of frictional resistance to any stress tending to withdraw the fastener as taught by Rosenberg.

41. With respect to claim 126, as noted above, Emmett teaches the use of load bearing plugs including a hollow portion.

Allowable Subject Matter

43. The following is a statement of reasons for the indication of allowable subject matter: Claims 76-88, 92-94, 95-103 and 108-120 are allowed.

44. The following is an examiner's statement of reasons for allowance: The prior art of record fails to teach or fairly suggest a semiconductor substrate processing chamber and accessory attachment interfacial structure as recited, wherein load bearing plugs are received in openings of the body and extending through the thermally insulative material, wherein at least some of the load bearing plugs are entirely solid and at least some include a hollow portion. Further, no piece of properly combinable prior art was located that provided motivation for providing this feature in the prior art.

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Response to Arguments

45. Applicant's arguments filed 10 February 2006, as well as those presented in the 24 April 2006 interview, have been fully considered but they are not persuasive. Applicant argues that the claimed attachment means are different enough from what is explicitly disclosed in the prior art that a statement, also provided in the prior art that states that appropriate attachment means can be chosen from any means that would appropriately attach two portions of an interface structure, fails to render the recitation obvious. Examiner disagrees. Examiner points out that the passage of Tepman merely says that the two pieces are attached. It does not say they are screwed together. It is not limiting with respect to attachment means that may be used. One of ordinary skill in the art would realize that there are a plethora of means of attachment that could be used, some of which do not comprise threading, as claimed. The courts have ruled that "the test of obviousness is not whether features of the secondary reference may be bodily incorporated into the primary reference's structure, nor whether the claimed invention is expressly suggested in any one or all of the references, rather the test is what the combined teachings would have suggested to those of ordinary skill in the art." *Ex parte Martin* 215 USPQ 543, 544 (PO Bd Pat App 1981).

Conclusion

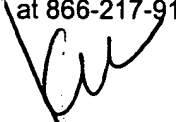
Any inquiry concerning this communication or earlier communications from the examiner should be directed to Karla Moore whose telephone number is 571.272.1440. The examiner can normally be reached on Monday-Friday, 8:30am-5:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC)

at 866-217-9197 (toll-free).



Kara Moore
Primary Examiner
Art Unit 1763
1 May 2006